

# Update from the Spanish future collider network

Micro-strip detectors with intrinsic gain

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Lessons from ILD-FTD design & mockup

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CLIC workshop, CERN, January 2015

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\*with special thanks to Ladislav Andricek, José Deltoro, David Santoyo and Ivan Vila

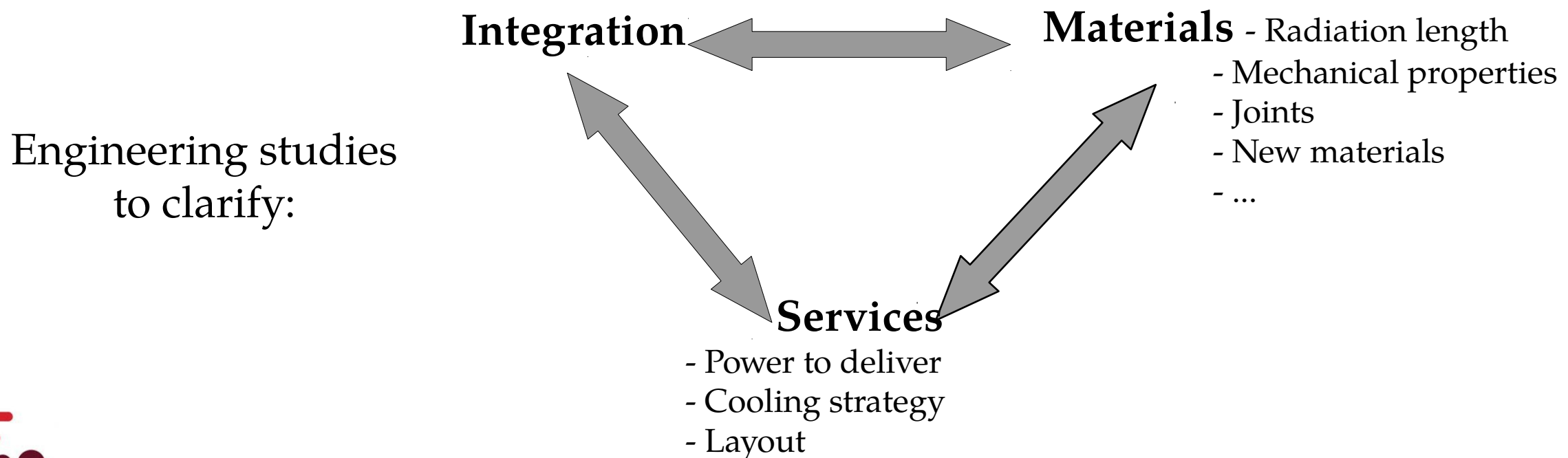
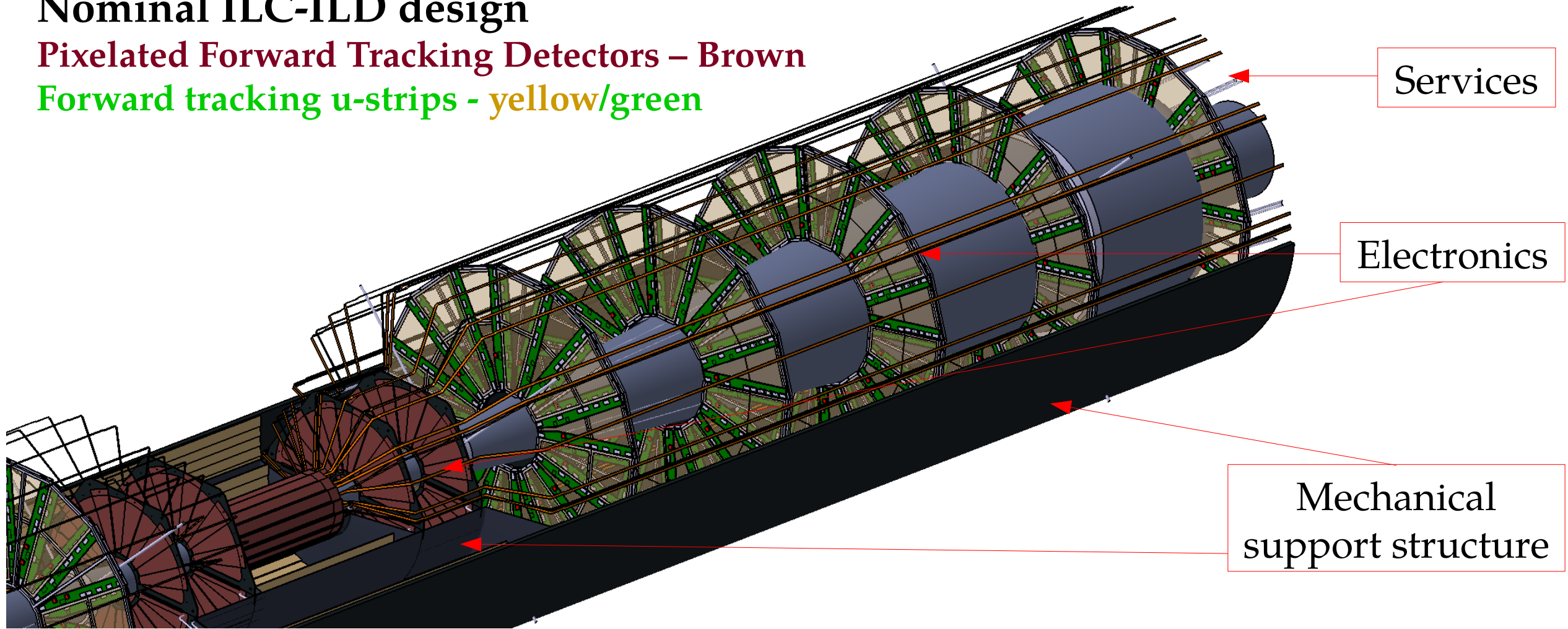


# Introduction

Nominal ILC-ILD design

Pixelated Forward Tracking Detectors – Brown

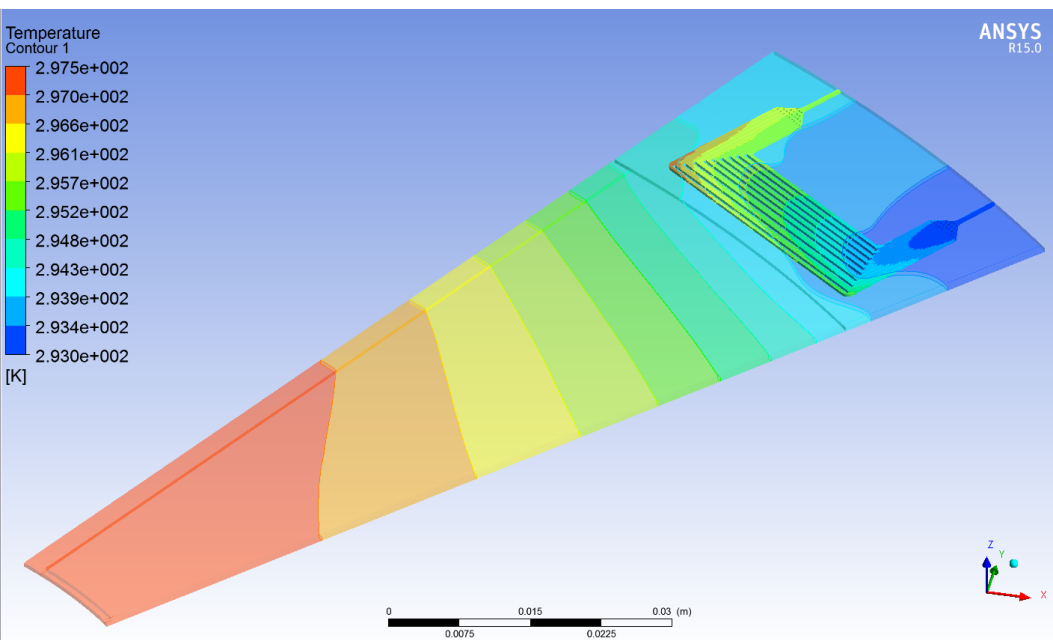
Forward tracking u-strips - yellow/green



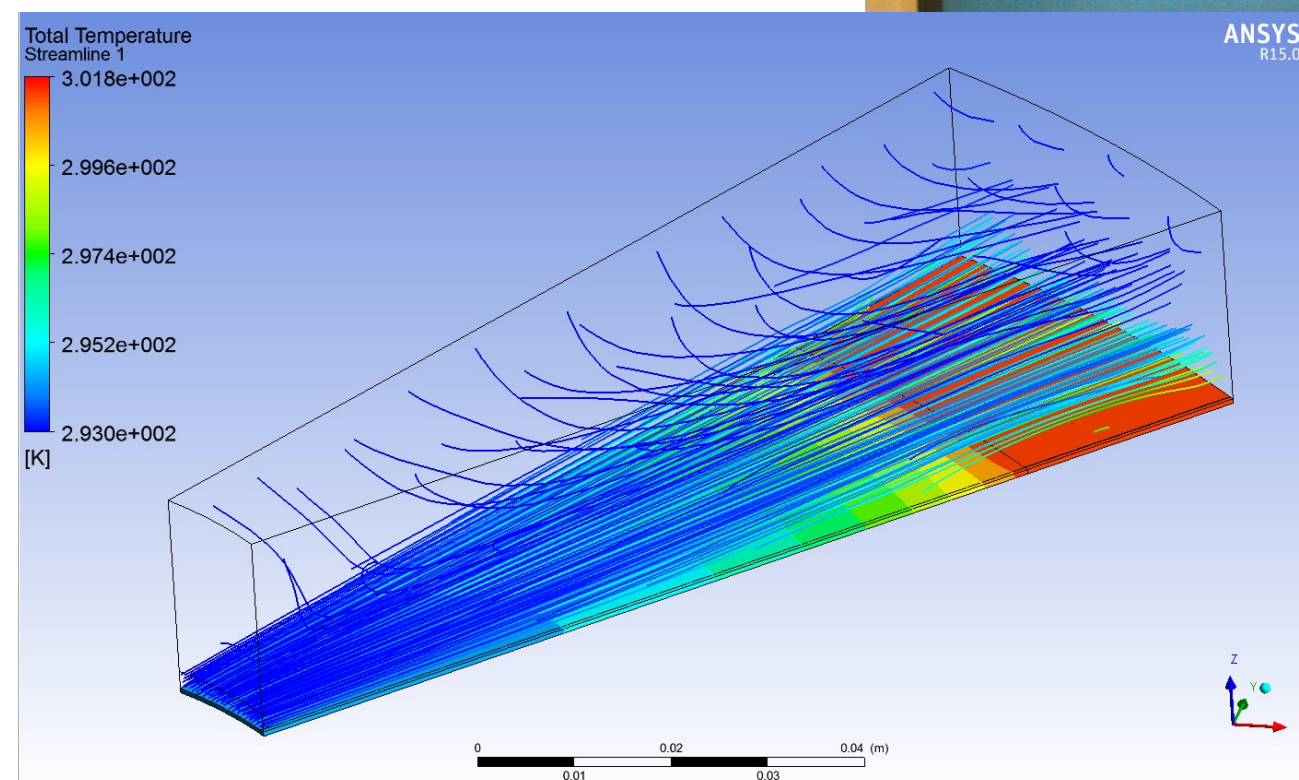


# Cooling strategy

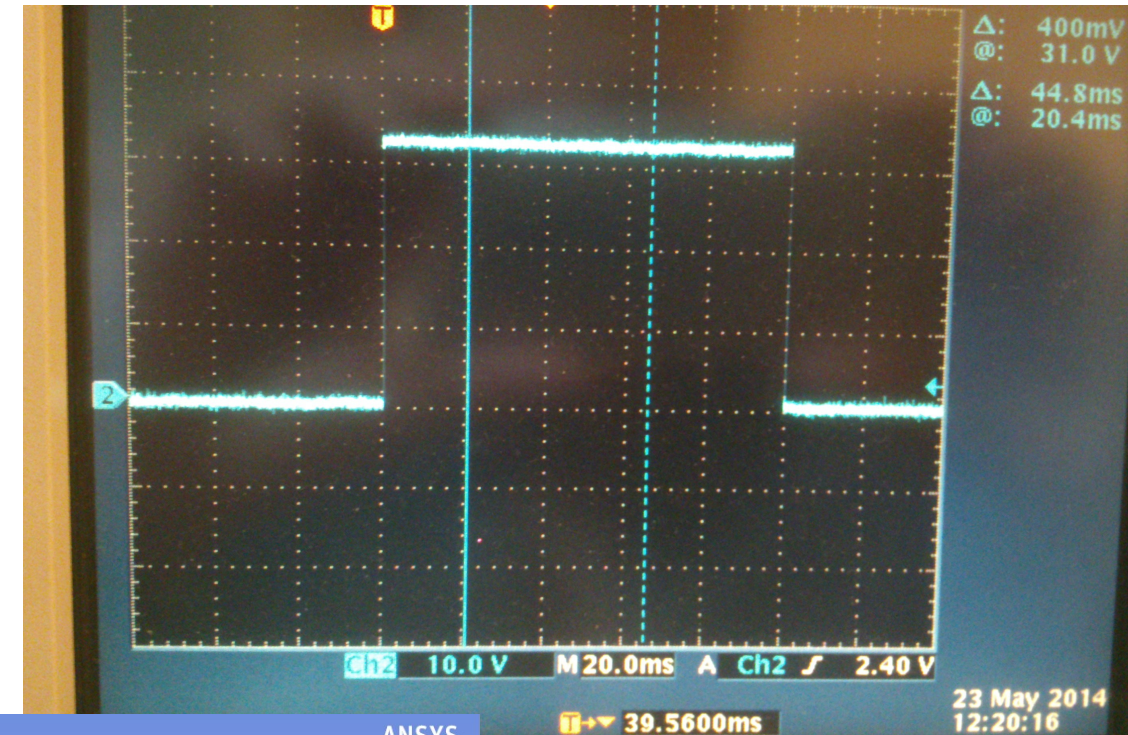
Micro Channel Cooling  
(IFIC-Bonn-HLL AIDA-H2020)



Air cooling



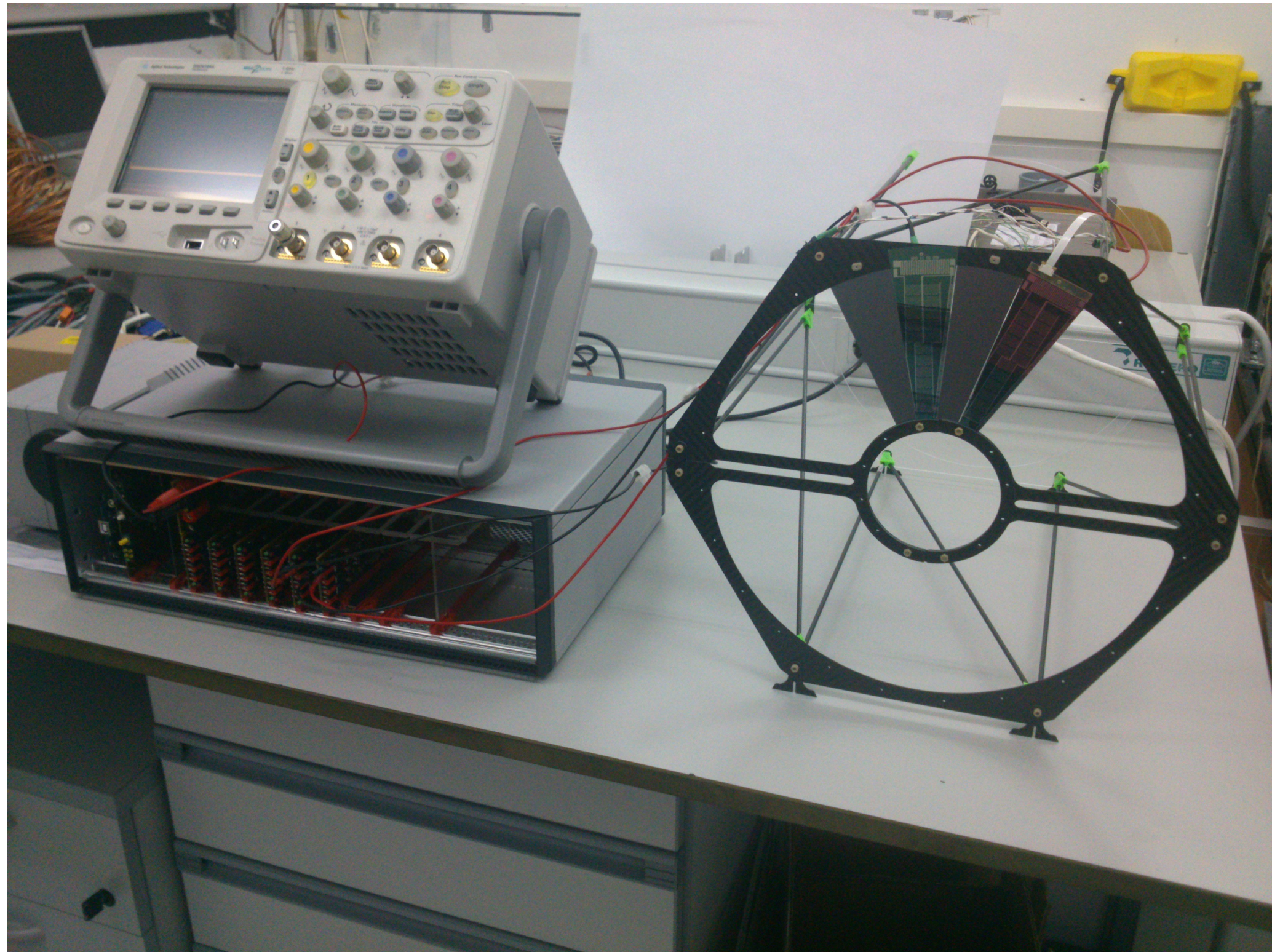
Power Pulsing





# First generation mock-up

IFIC copy of the  
AIDA pulsing  
power supply  
(AIDA  
deliverable  
report )



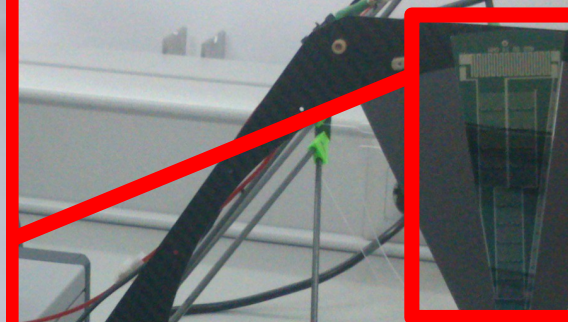


# First generation mock-up

Mechanical samples for 50  $\mu\text{m}$  petals based on the DEPFET all-silicon concept (L. Andricek, HLL)

Frame, end-of-petal,  
balcony:  $\sim 450\ \mu\text{m}$

Ultra-thin sensitive area: down to  $50\ \mu\text{m}$



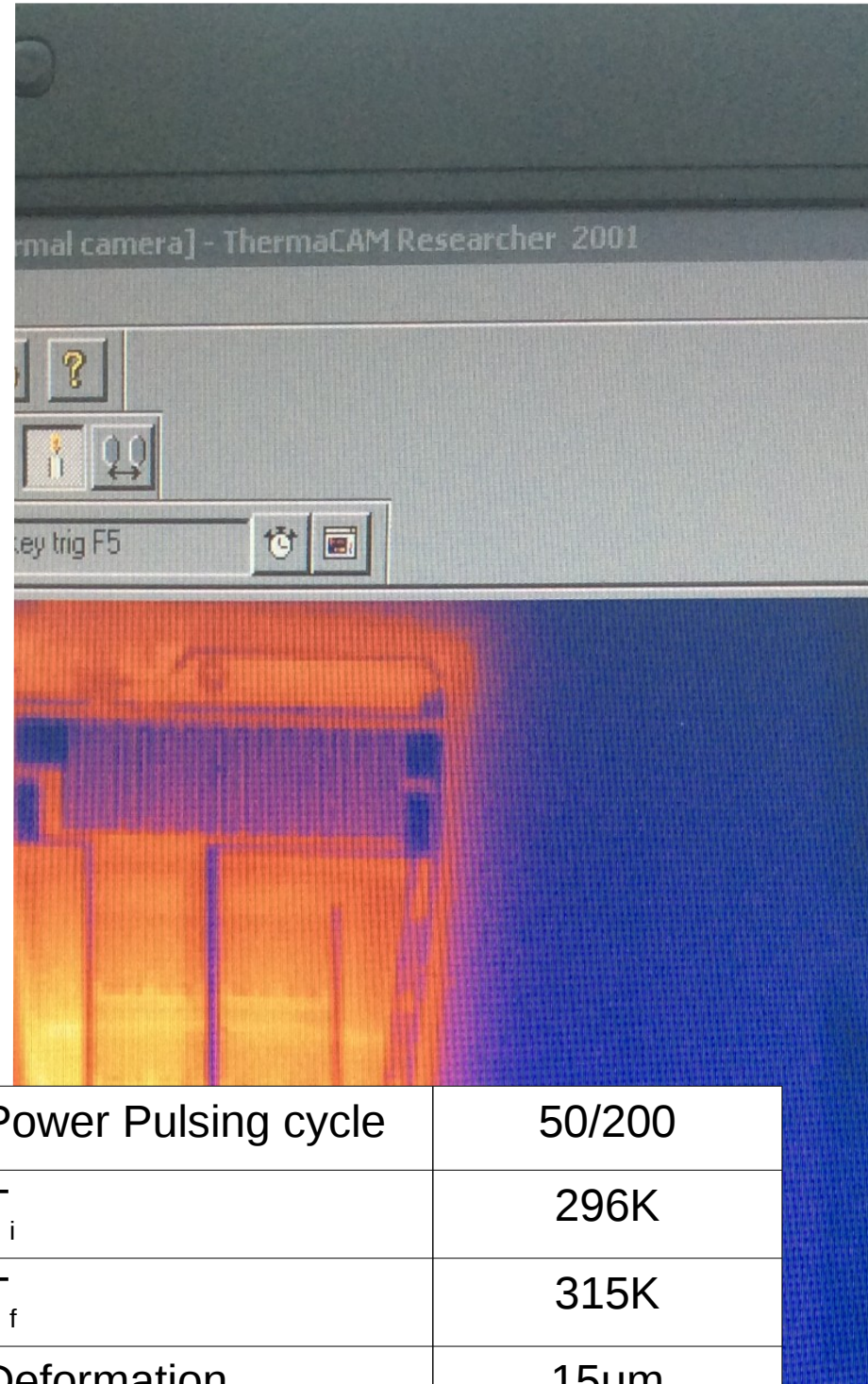


# Heat load & deformation

Nominal heat load (x2) without cooling leads to significant static deformation.

Extensive searches for dynamic deformations on ms time scale due to pulsed power (Bragg fibers, capacitive sensor, laser sensor)

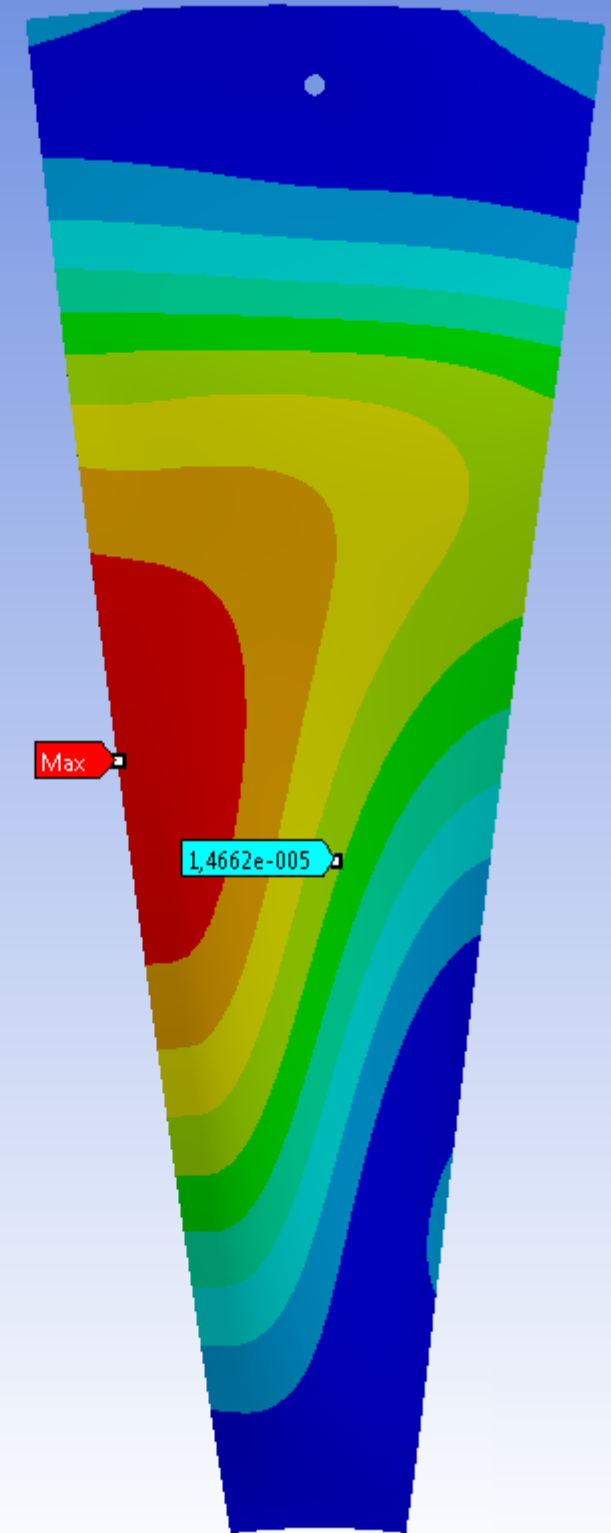
No effect observed, seems negligible.



Power Pulsing cycle	50/200
$T_i$	296K
$T_f$	315K
Deformation	15 $\mu$ m

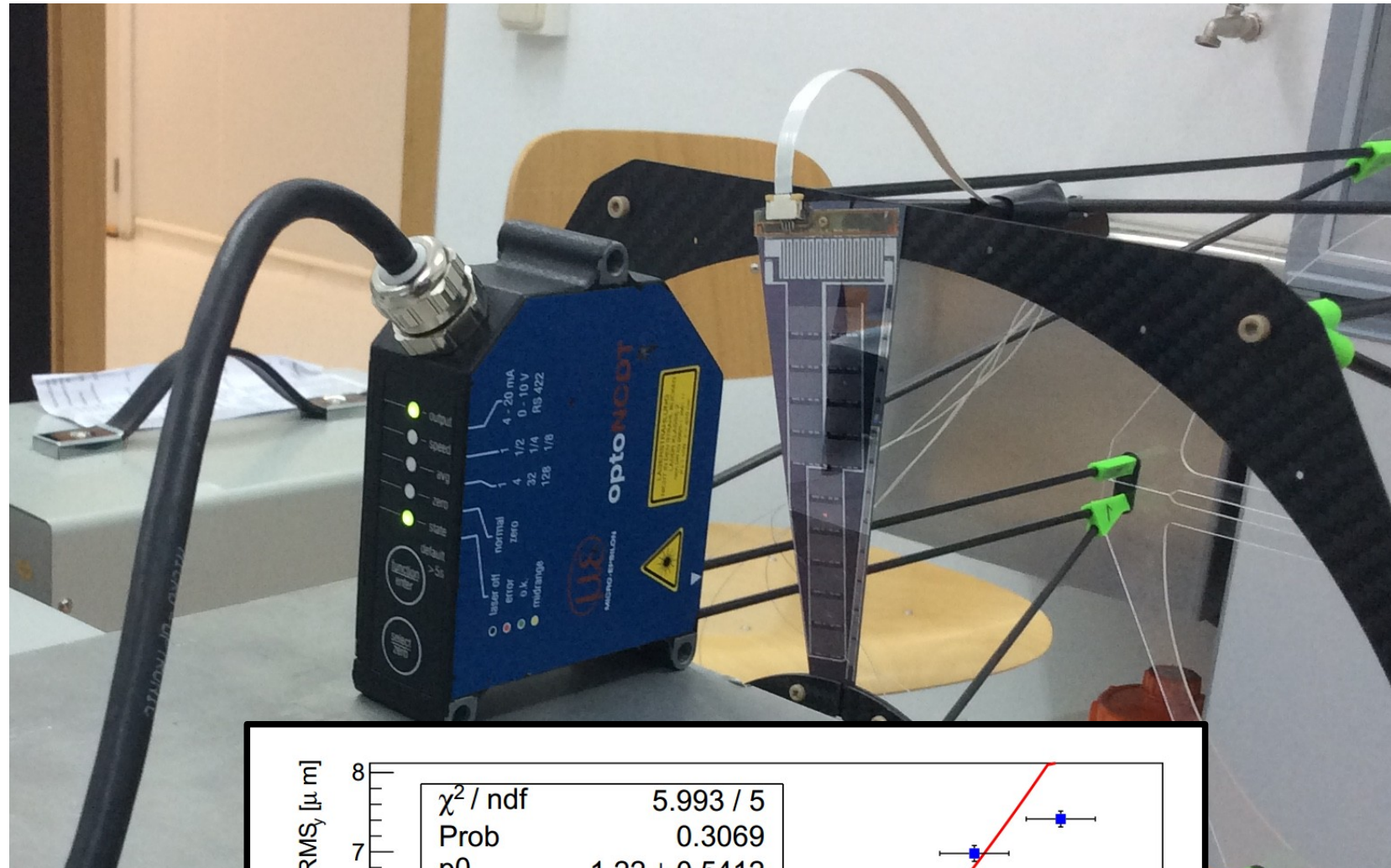
B: Static Structural  
Total Deformation  
Type: Total Deformation  
Unit: m  
Time: 1  
09/01/2015 15:28

2,5184e-5 Max  
2,2386e-5  
1,9588e-5  
1,6789e-5  
1,3991e-5  
1,1193e-5  
8,3947e-6  
5,5965e-6  
2,7982e-6  
0 Min

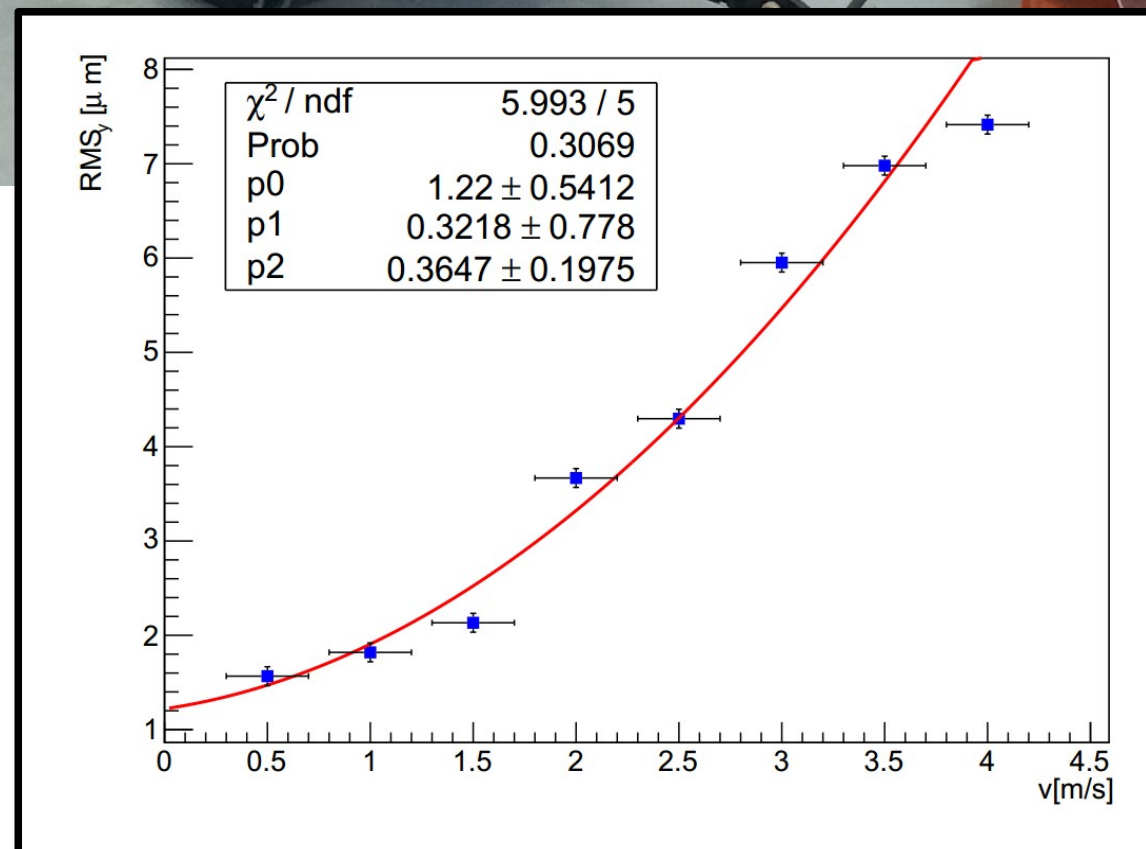


# Air flow & deformation

A laminar air flow in front of the disk, with a moderate speed of 1m/s, is sufficient to remove the nominal DEPFET heat load (assuming 1/25 duty cycle for power pulsing, IEEE TNS 60-2-2, arXiv:1212.2160)

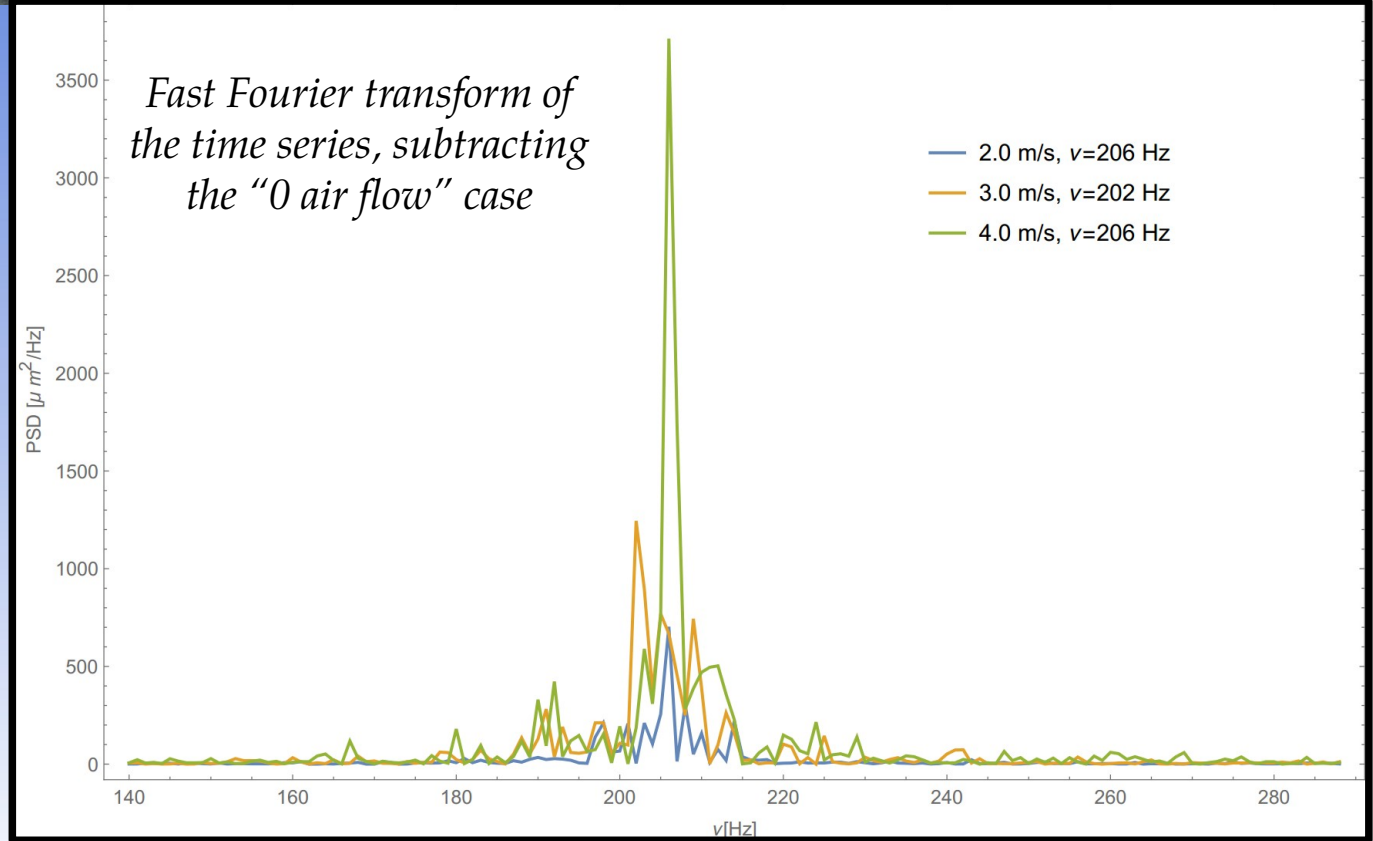
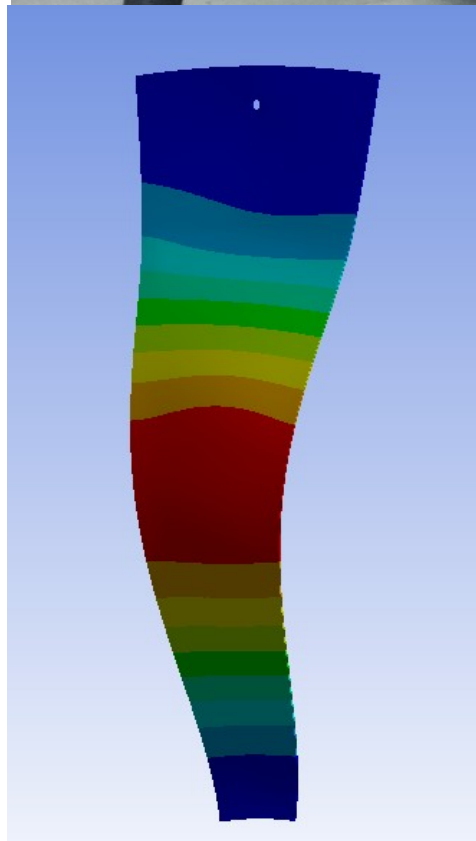
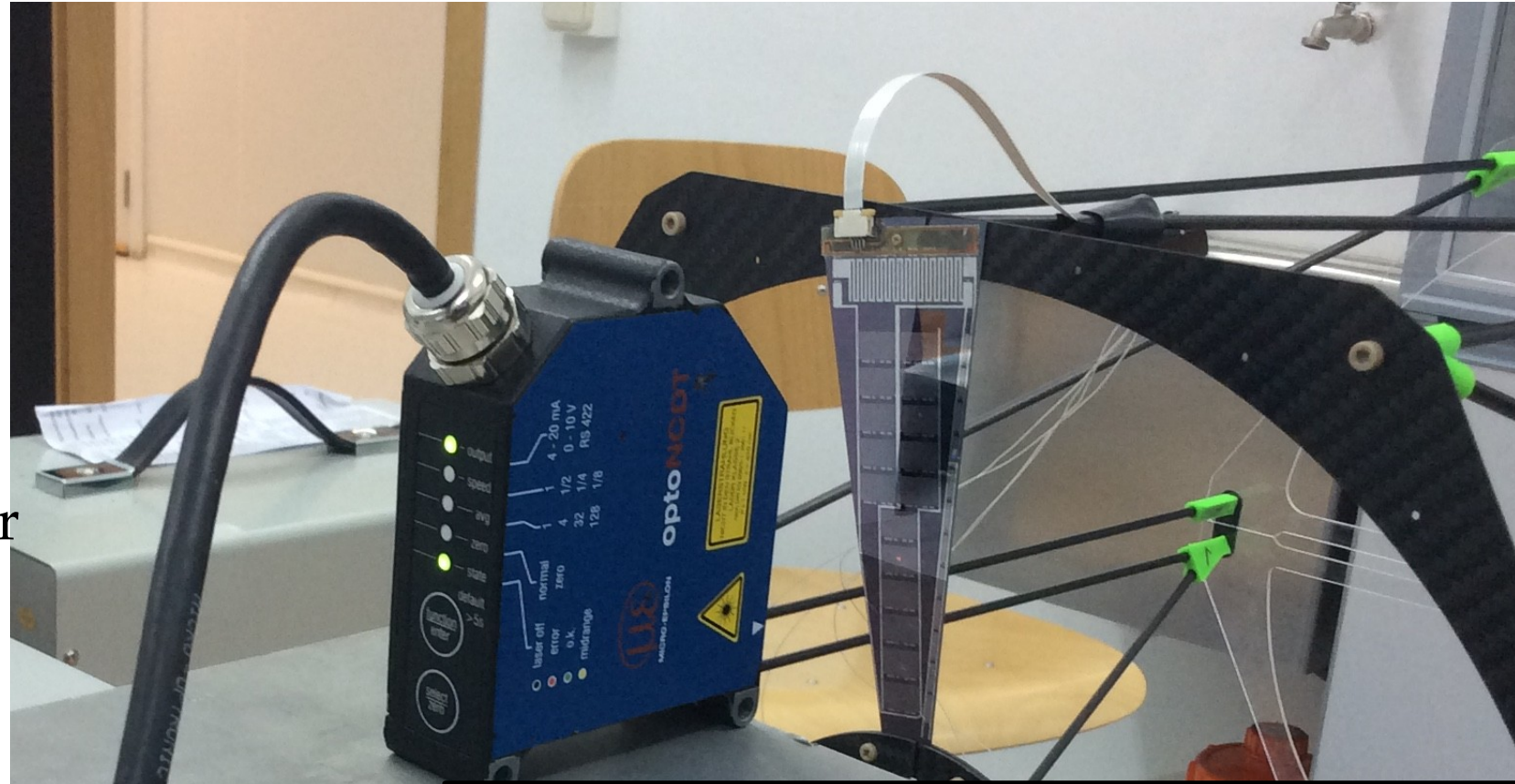


Air flow does introduce slight vibrations. For large air speed these become sizeable wrt the intrinsic resolution.





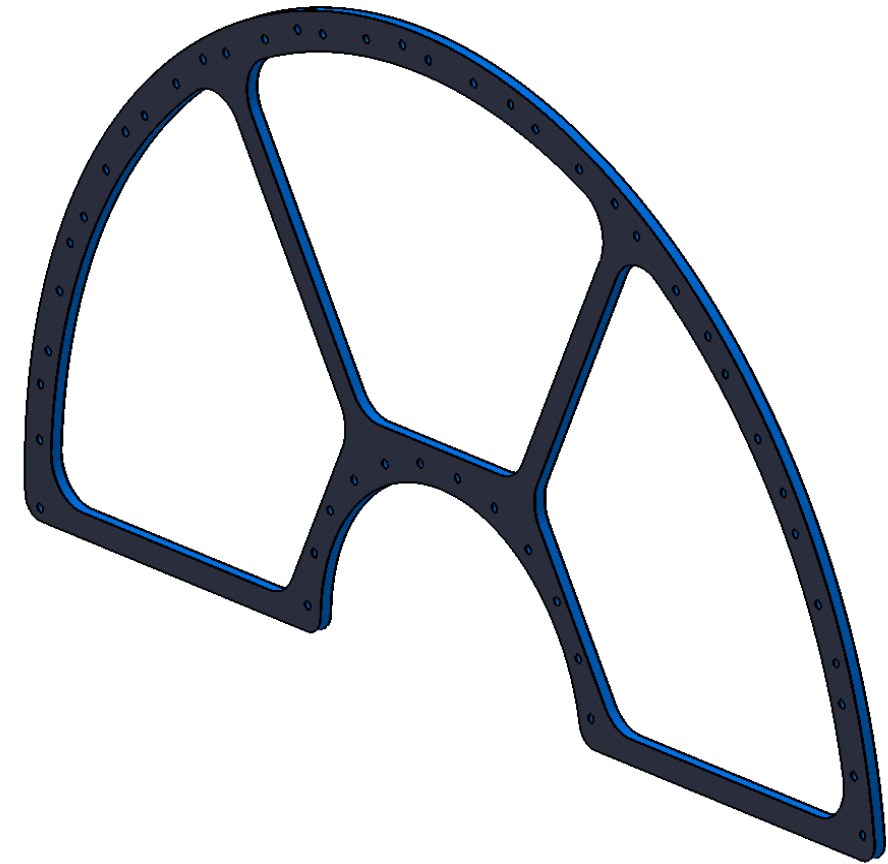
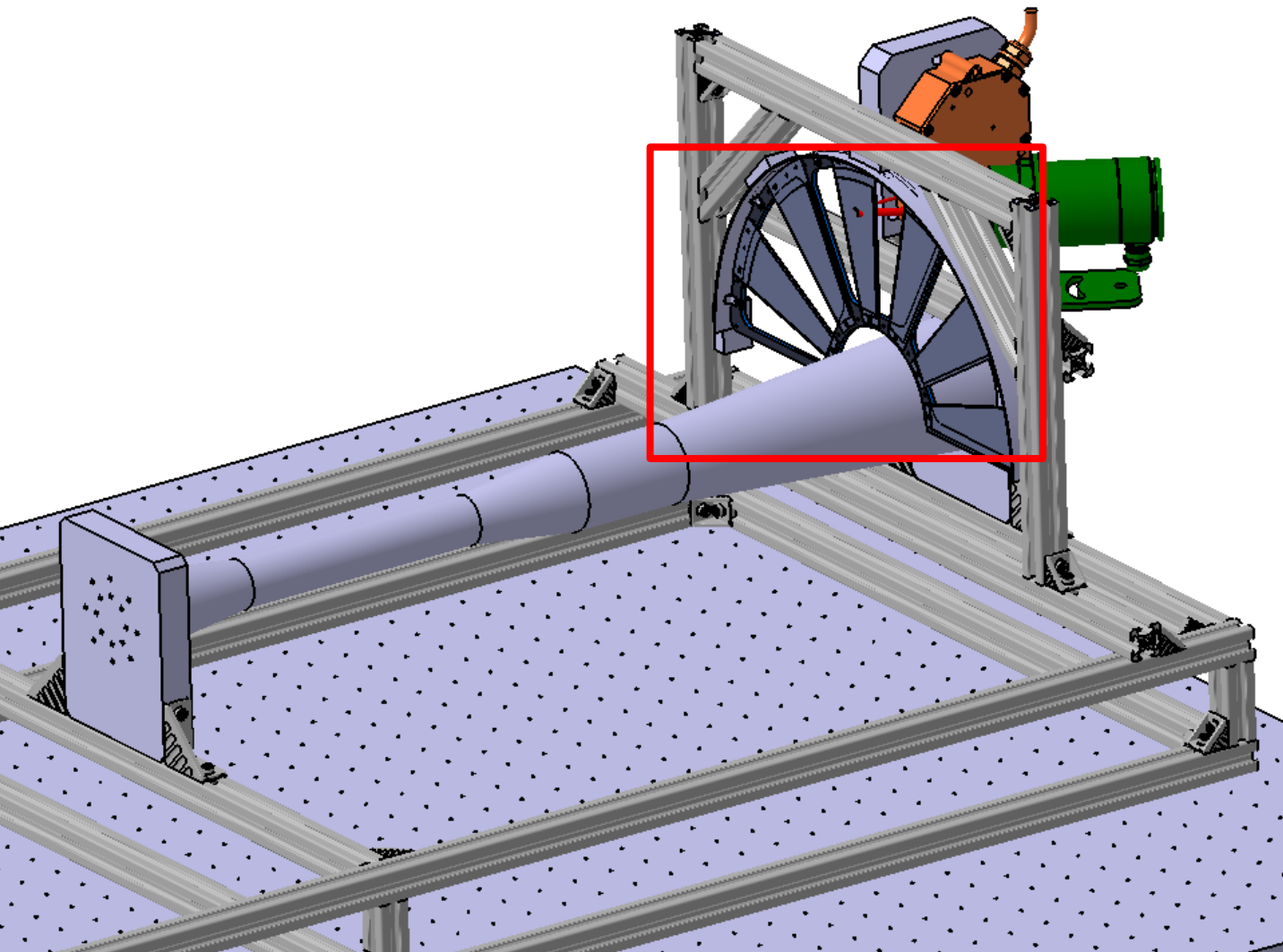
# Air flow & deformation





# Second generation mock-up (first half 2015)

More sophisticated CF support structures are being designed and will be produced at INTA (Spanish Aerospace Institute)



Sandwich:  $[0(t=0,07), 60(t=0,07), -60(t=0,07), \text{core}(t=2-3)]$

CFRP: M55J;  
epoxy: cyanate-ester;  
core: airex, nomex, rohacell  
(mechanical and radiation tests needed)

$R_{\text{int}} = 35\text{mm}; 45\text{mm}$

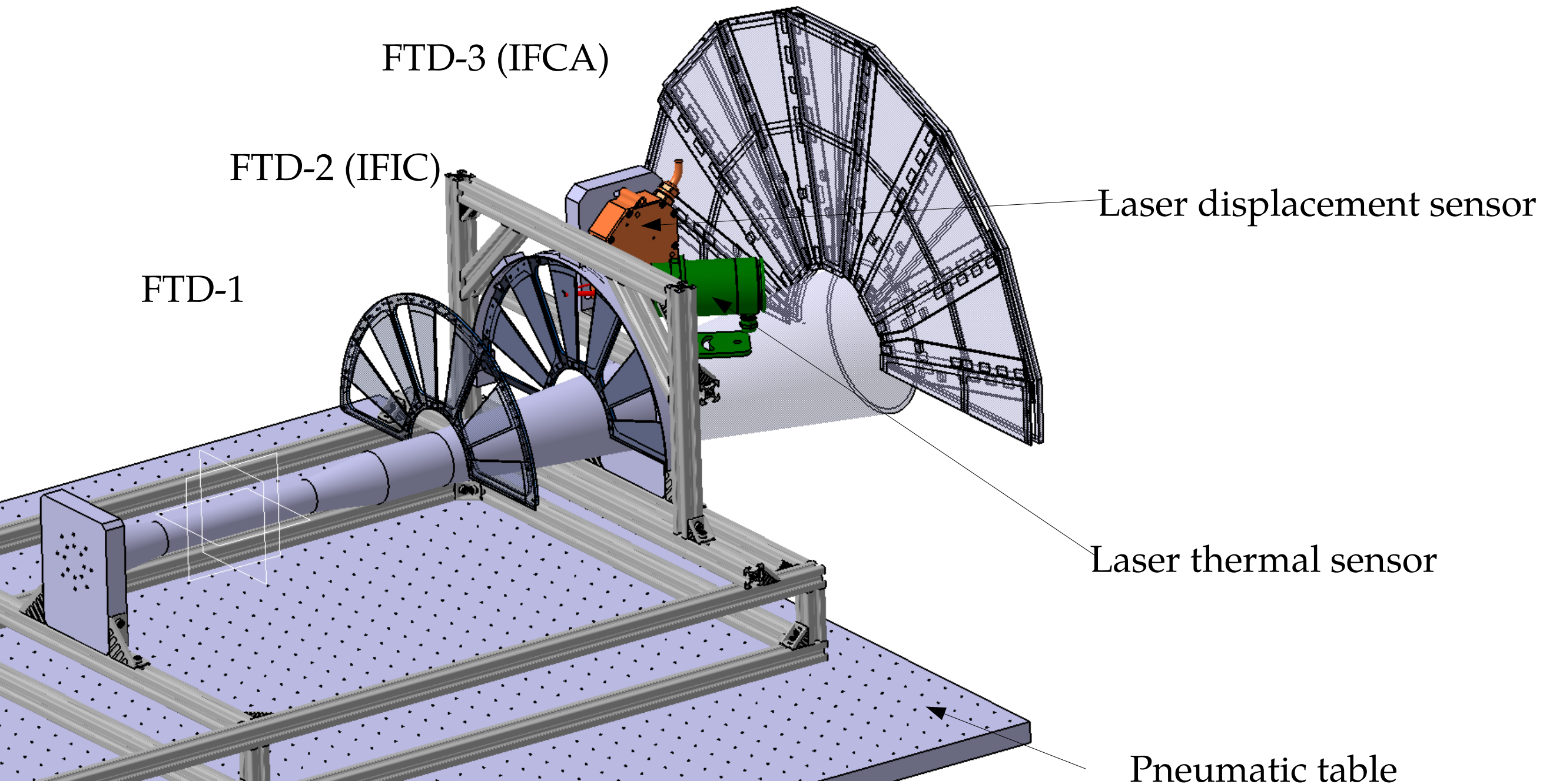
$R_{\text{ext}} = 150\text{mm}$

$m=10\text{g}$  ( $X/X_0 \sim 0,04\%$ )





# Complete FTD mock-up (2015+)





## Avalanche Detectors with Low Internal Gain

► Exploit **avalanche** phenomenon of a **n+p junction** polarized in reverse mode.

► **LGAD = Low Gain Avalanche Detectors**

**Signal multiplication:** *charge carriers accelerated in high electric field can release further carriers that add to the signal*

**Linear regime:** *signal remains proportional to primary ionization signal (avoid Geiger mode)*

- ❑ Higher **signal to noise ratio** (S/N)
- ❑ => Better spatial resolution
- ❑ => Less material
- ❑ => Rad-hard performance (RD50 LGAD)

**Use CNM in-house processes: capability for thin 6" wafers, full custom implants and segmentation (pixel/strips)**

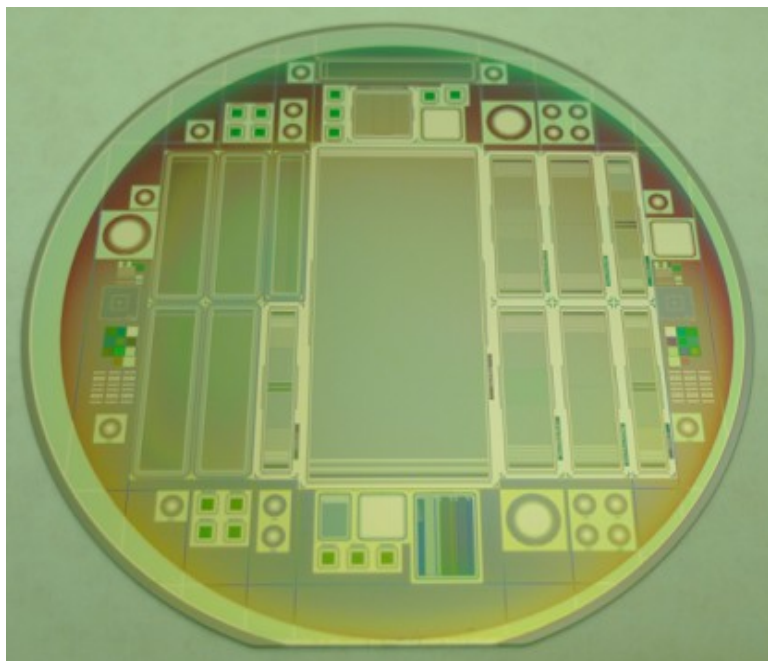


Figure 1. General view of a wafer with the new **resistive microstrip** detectors fabricated at IMB-CNM clean room

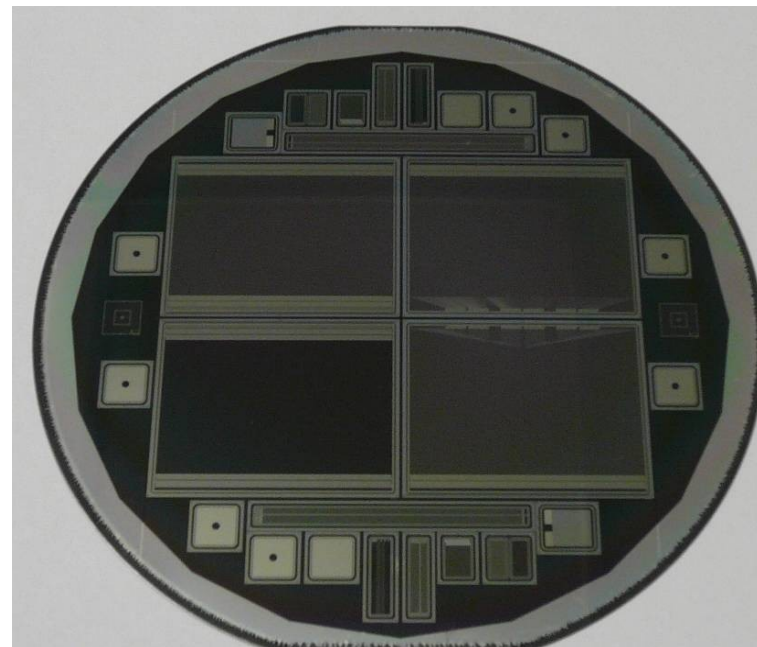


Figure 2. General view of a wafer with **thin substrate microstrips** detectors fabricated at IMB-CNM clean room

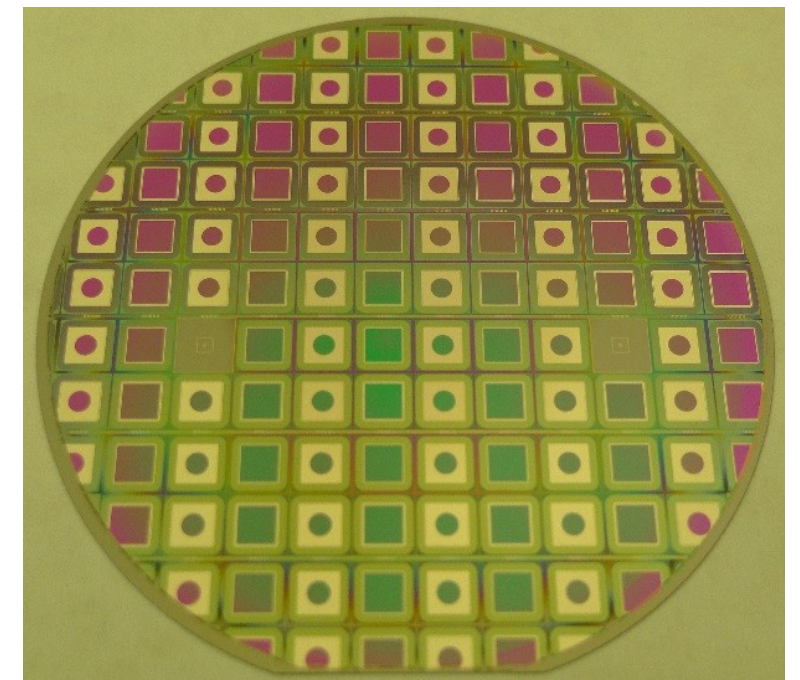
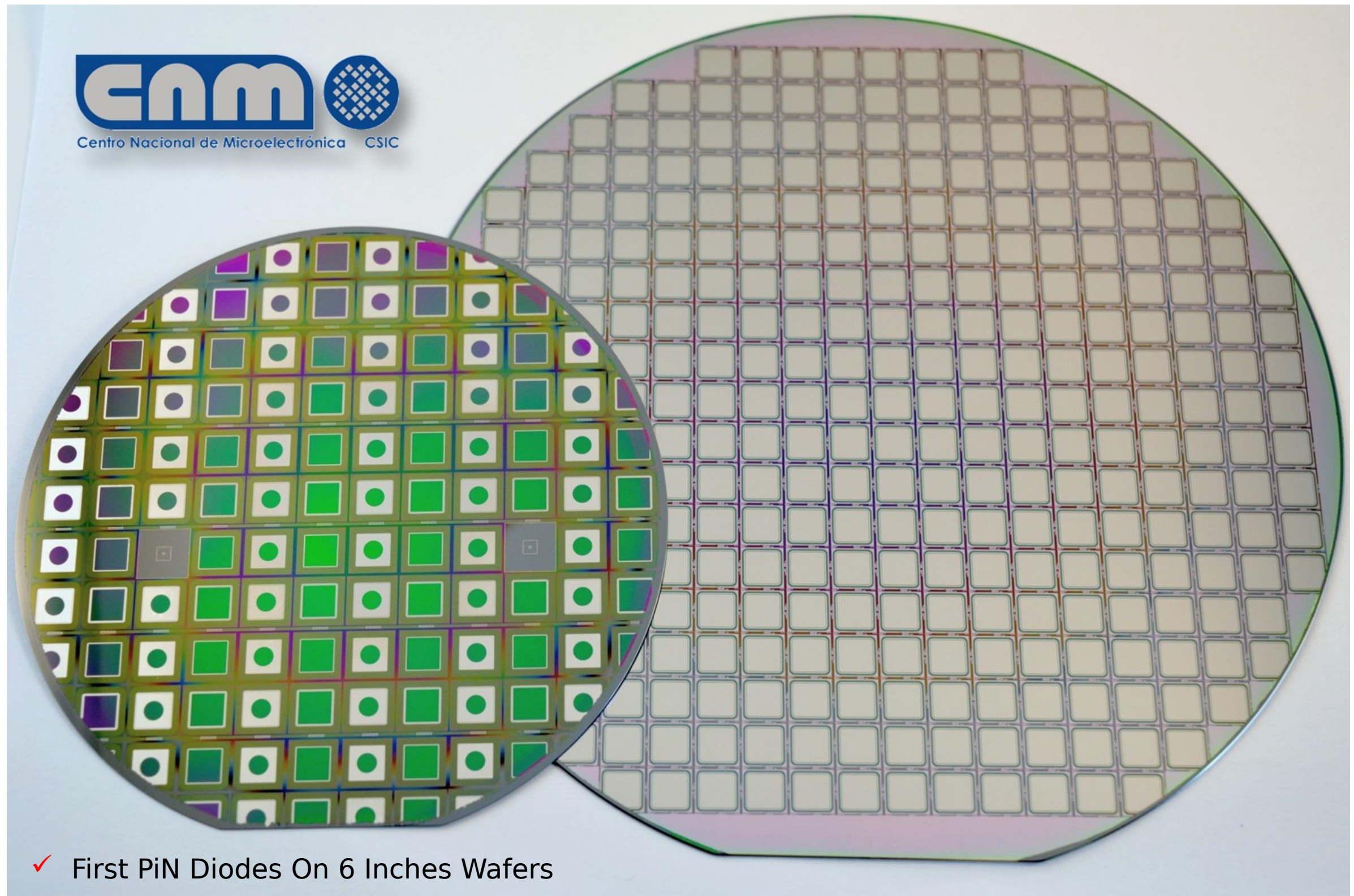


Figure 3. General view of a wafer with **LGAD** detectors (APD evolution) fabricated at IMB-CNM clean room



## 6 inch Technological Process



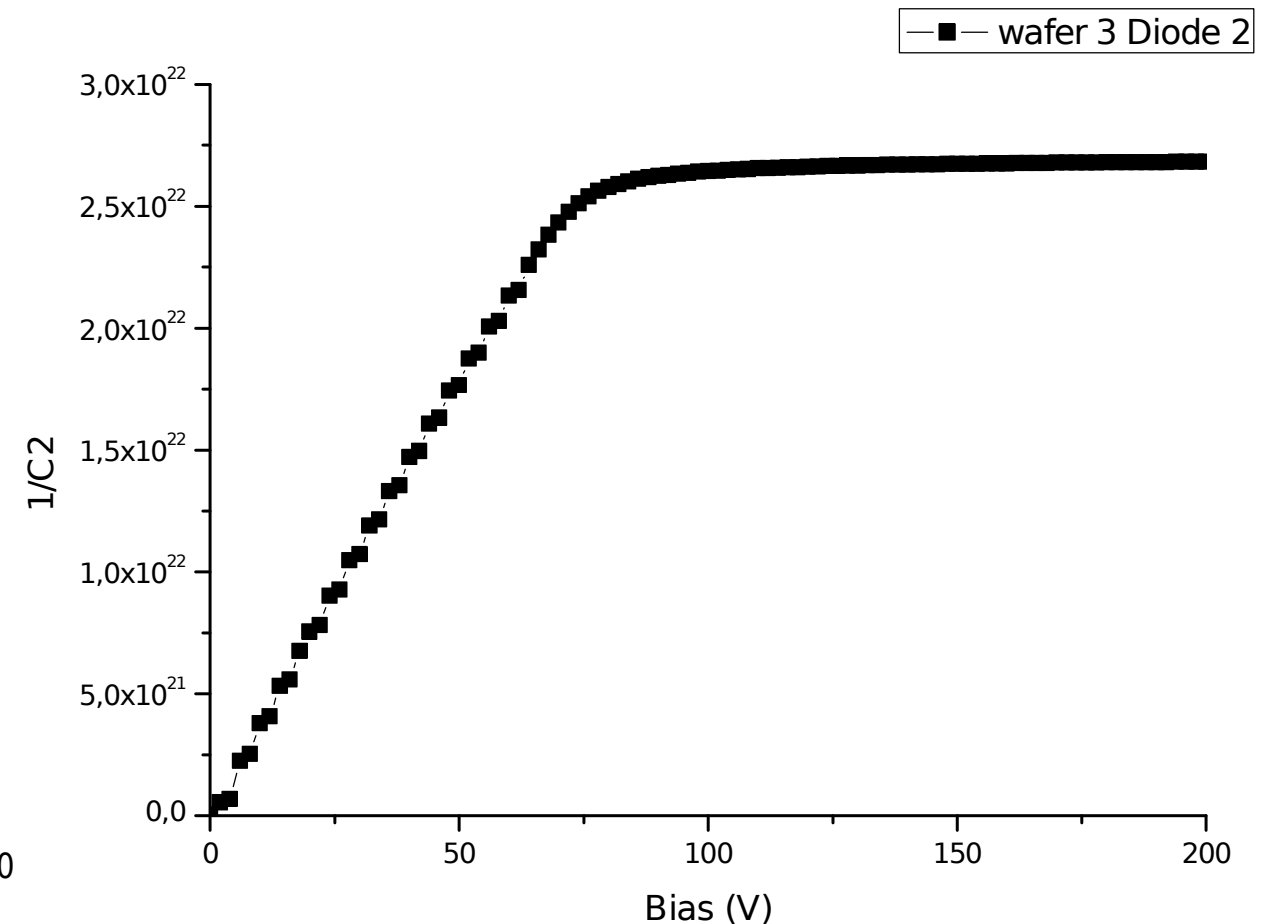
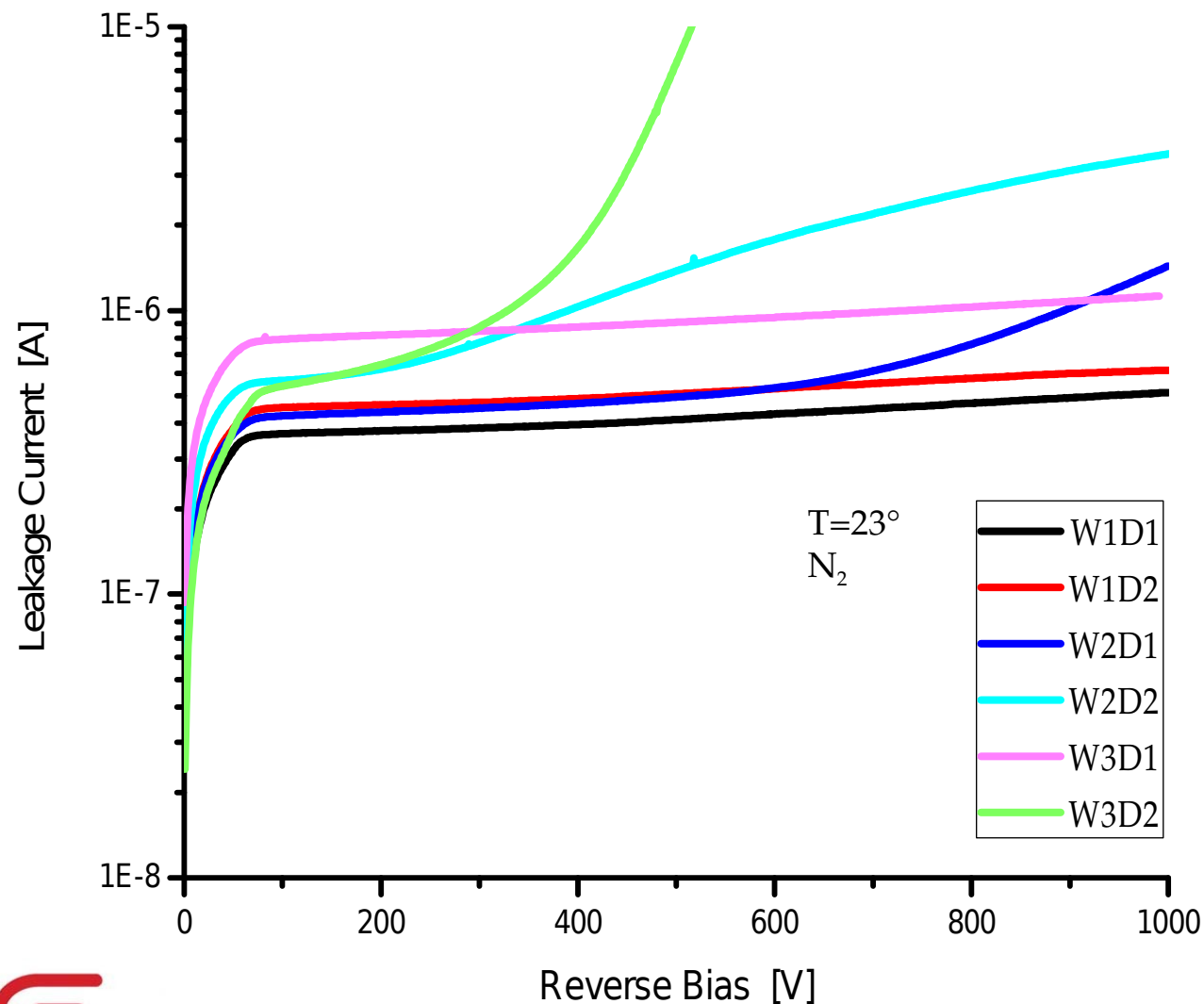


## 6 inch Technological Process

### First Results:

- ✓ **Good** electrical performances
- ✓ **Comparable** to **4 inch** technology PiN diodes

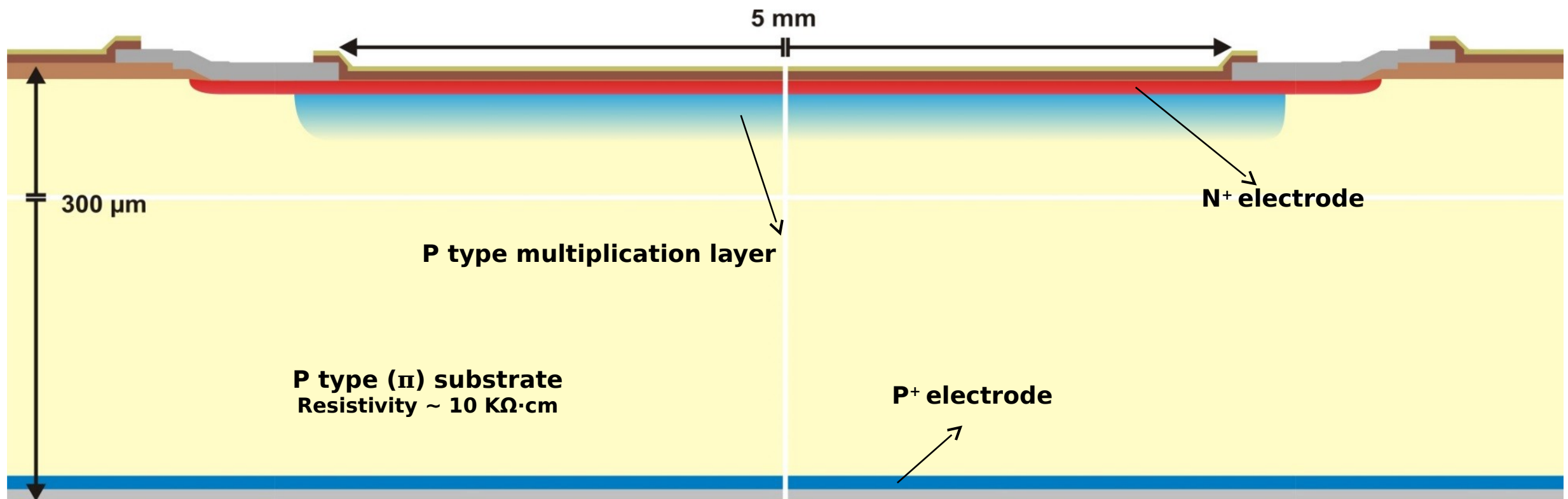
Run 7031 PiN Diodes - 6 inches wafer - I-V Curves





## Low Gain Avalanche Detector (LGAD)

- The goal: a **diode with multiplication** working in linear mode (proportional response).



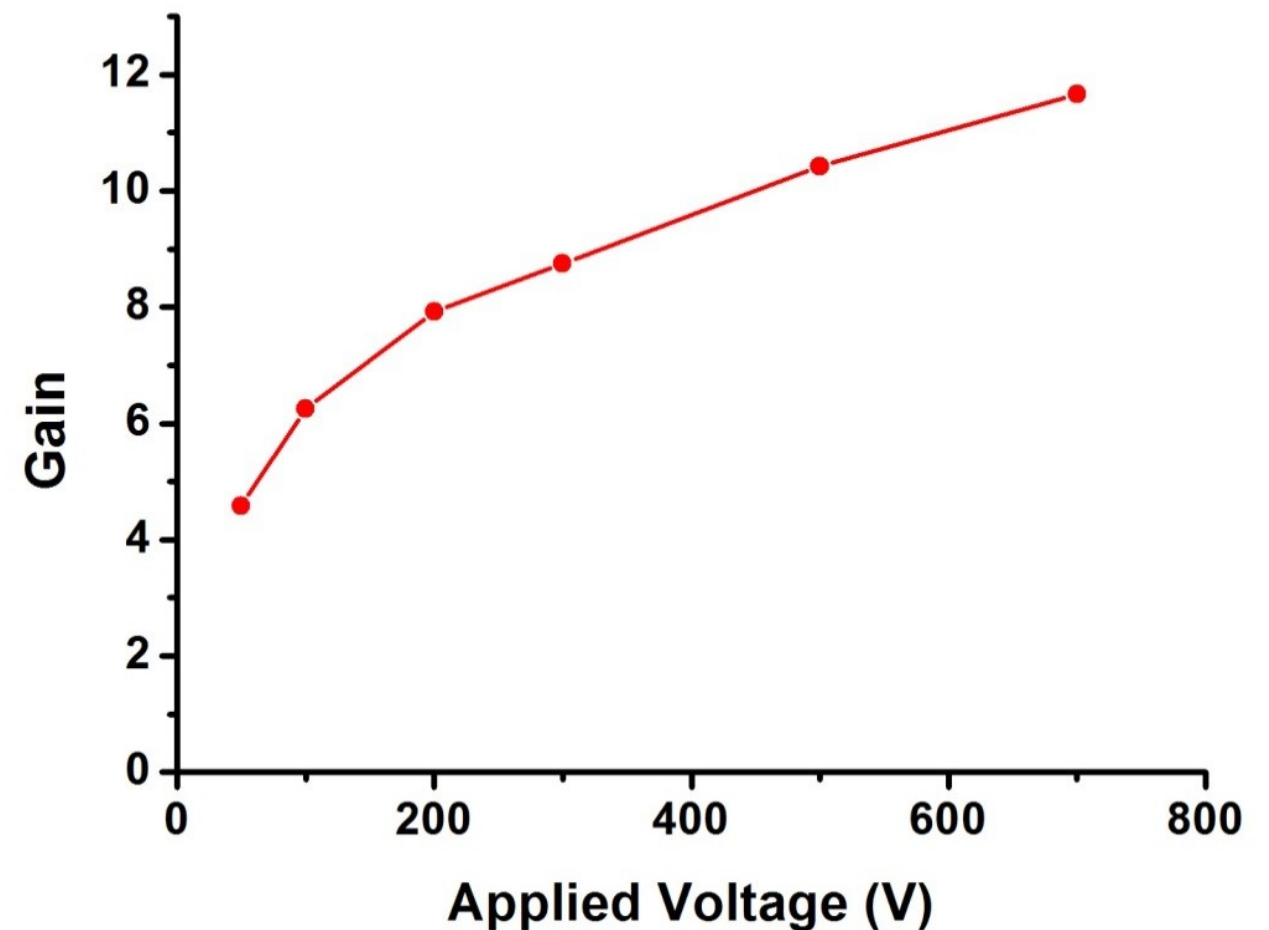
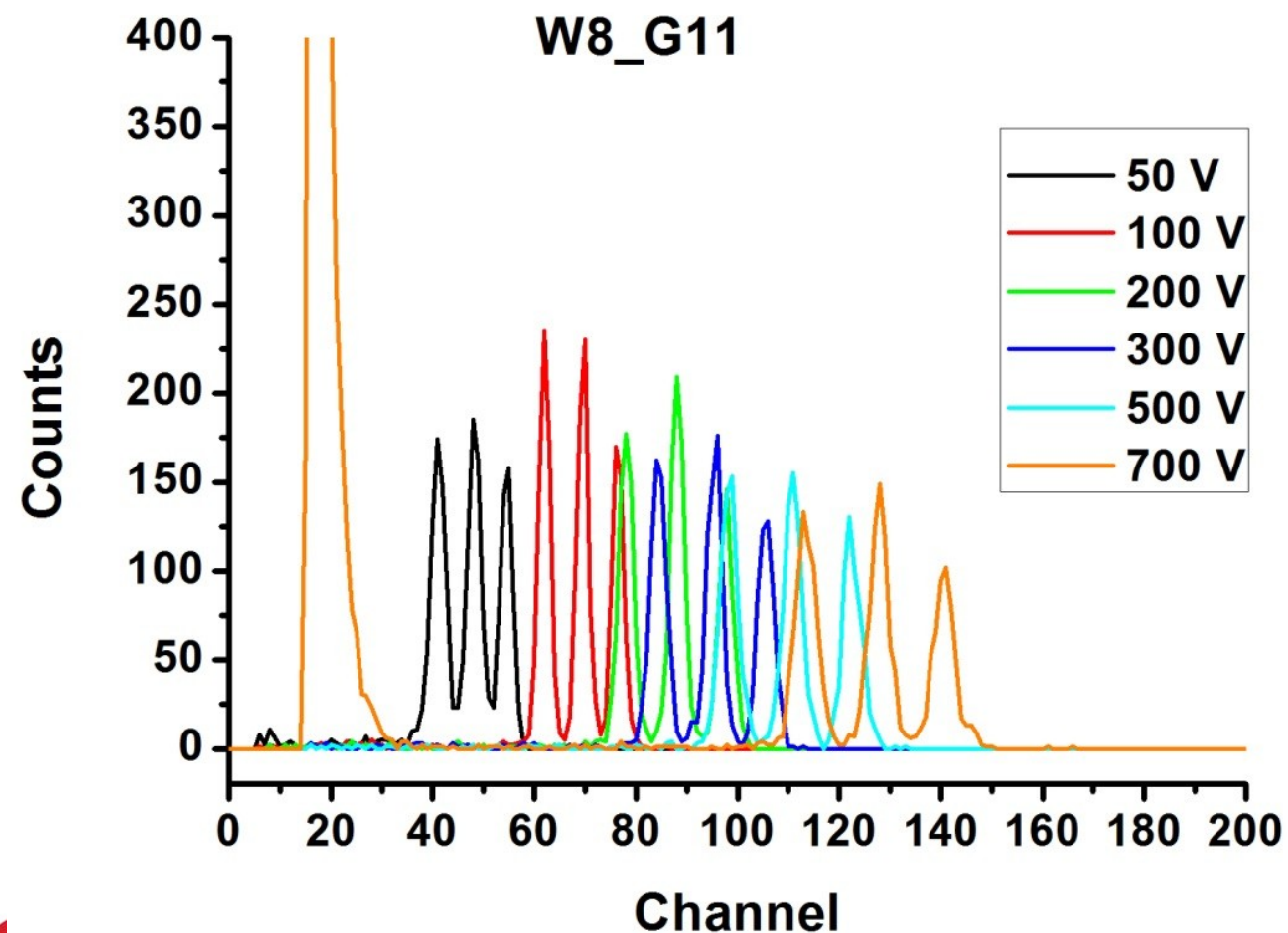
- Starting point: PiN-*pad* diode with an area of 5mm x 5mm.
  - ➡ **Structure**: highly resistive *p*-type substrate
    - ➡ ***n*+ and *p*+ diffusions** for the electrodes
    - ➡ ***p* diffusion** under the cathode
      - => enhance electric field => **multiplication layer**



## Charge Collection Measurements: Alpha Particles

□ Multiplication factor measured with tri-alpha radiation source ( $^{239}\text{Pu}/^{241}\text{Am}/^{244}\text{Cm}$ )

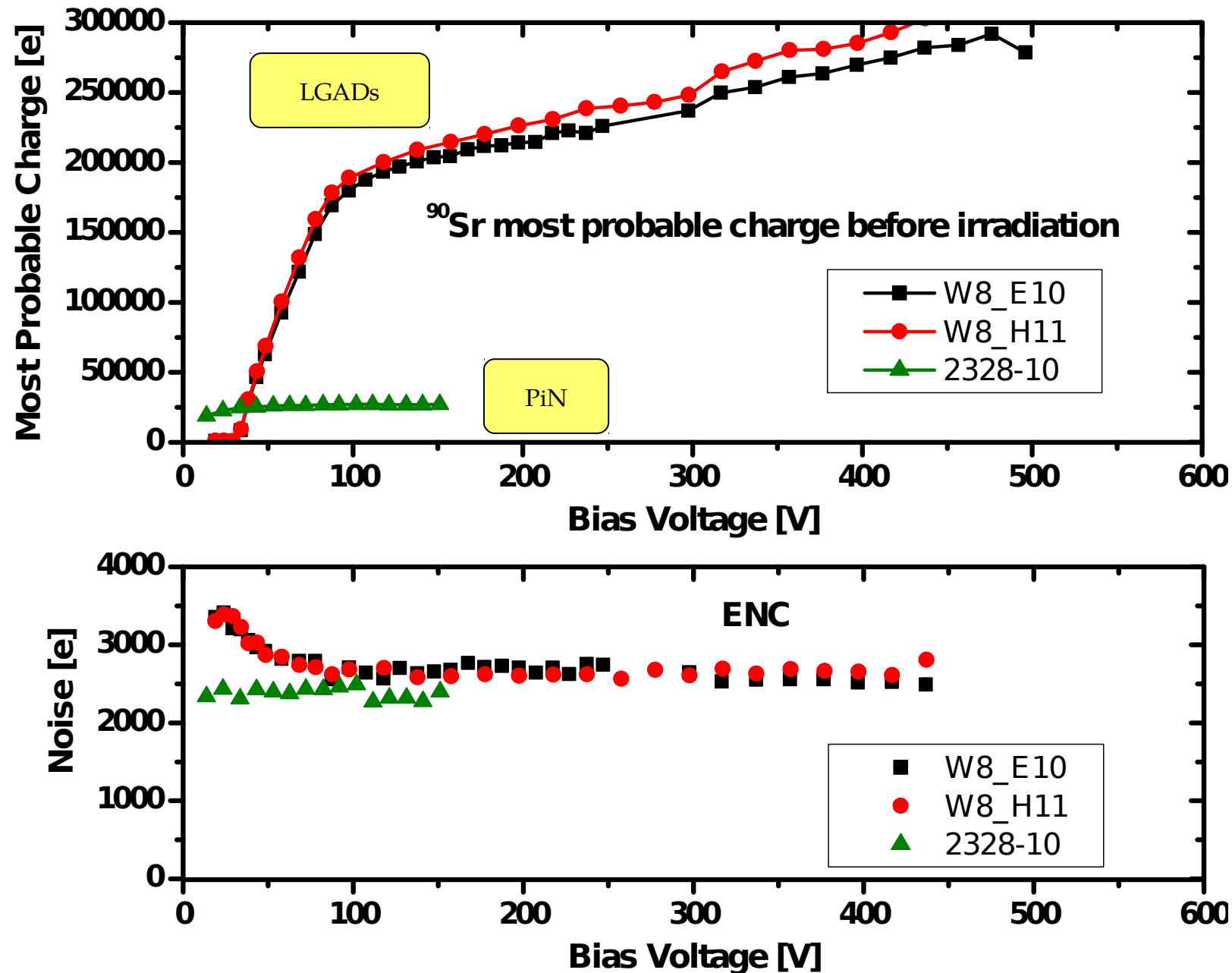
$$\text{Gain}_{@V} = \frac{\text{Central Peak Channel}_{@V}}{\text{Central Peak Channel}_{\text{No mult.}}}$$





## Charge Collection Measurements: Electrons (~mips)

- Charge collection measurements of *mips* with  $^{90}\text{Sr}$  source

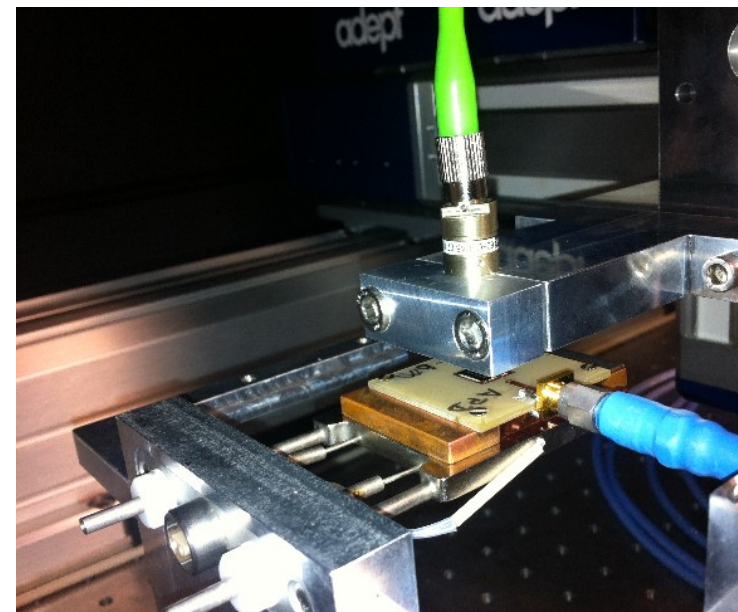
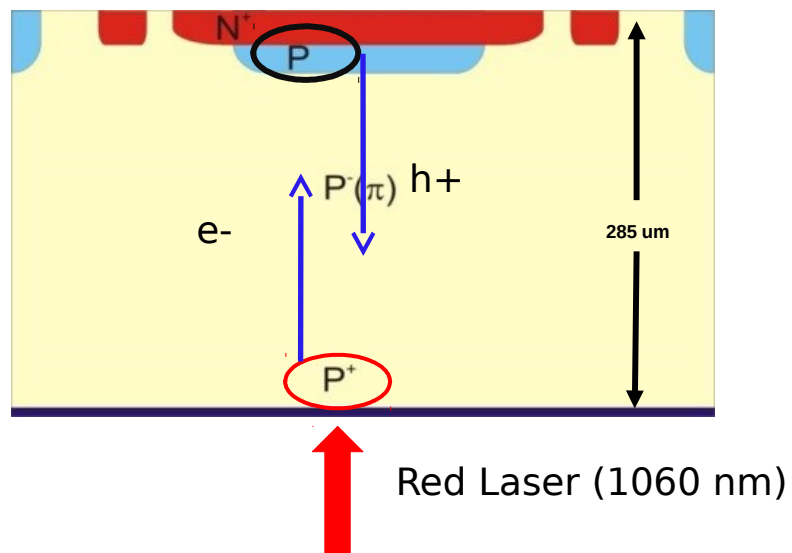
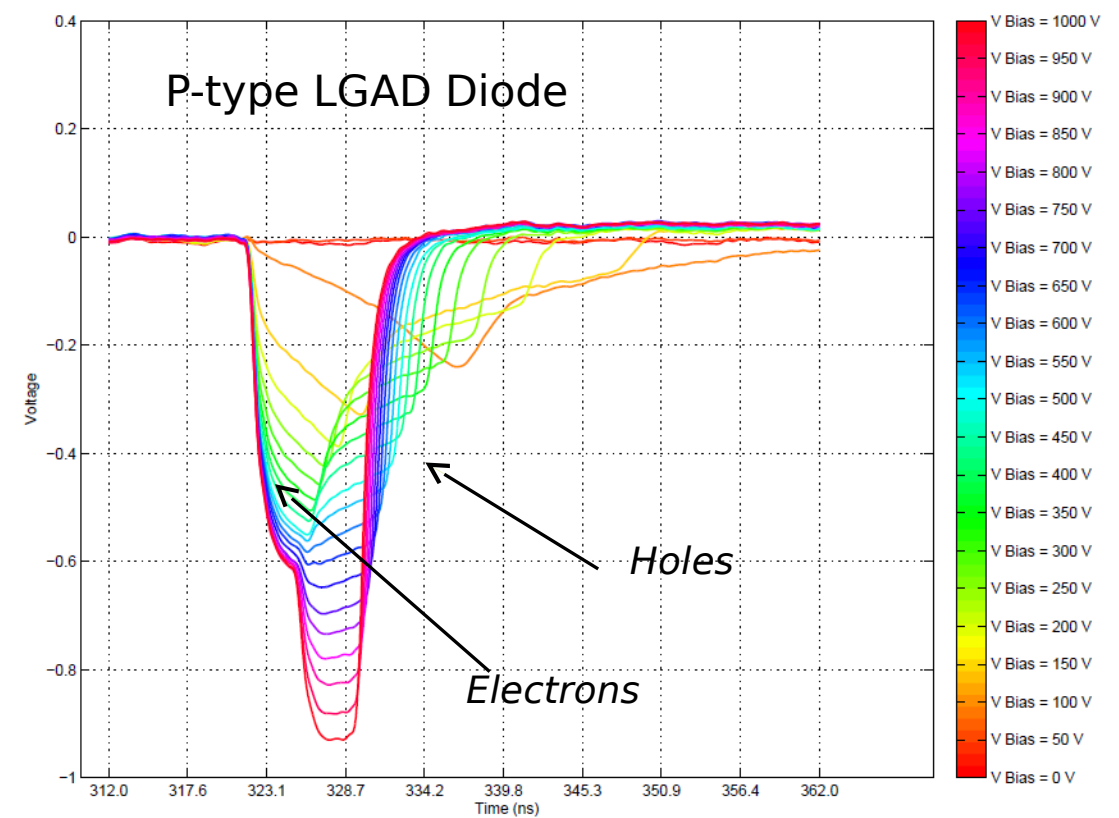
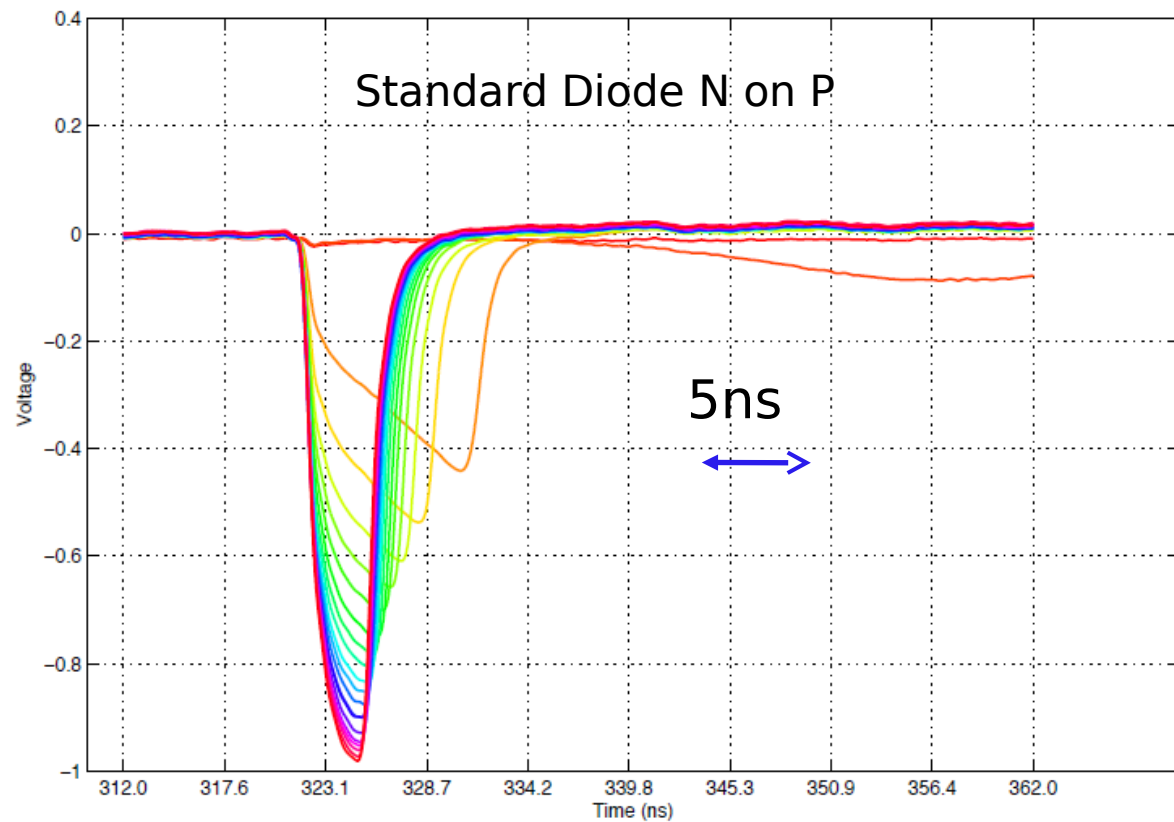


Measurements with LHC-style Front-End performed at the "Jozef Stefan" Institut, in Ljubljana, Slovenia

- ➡ Observed gain:  
Signal amplified by a factor 8 at 300V
- ➡ Compare with a commercial PiN:  
no significant **increase of the noise**

## Laser TCT Measurements

### Red Laser TCT Characterization. Bottom Injection

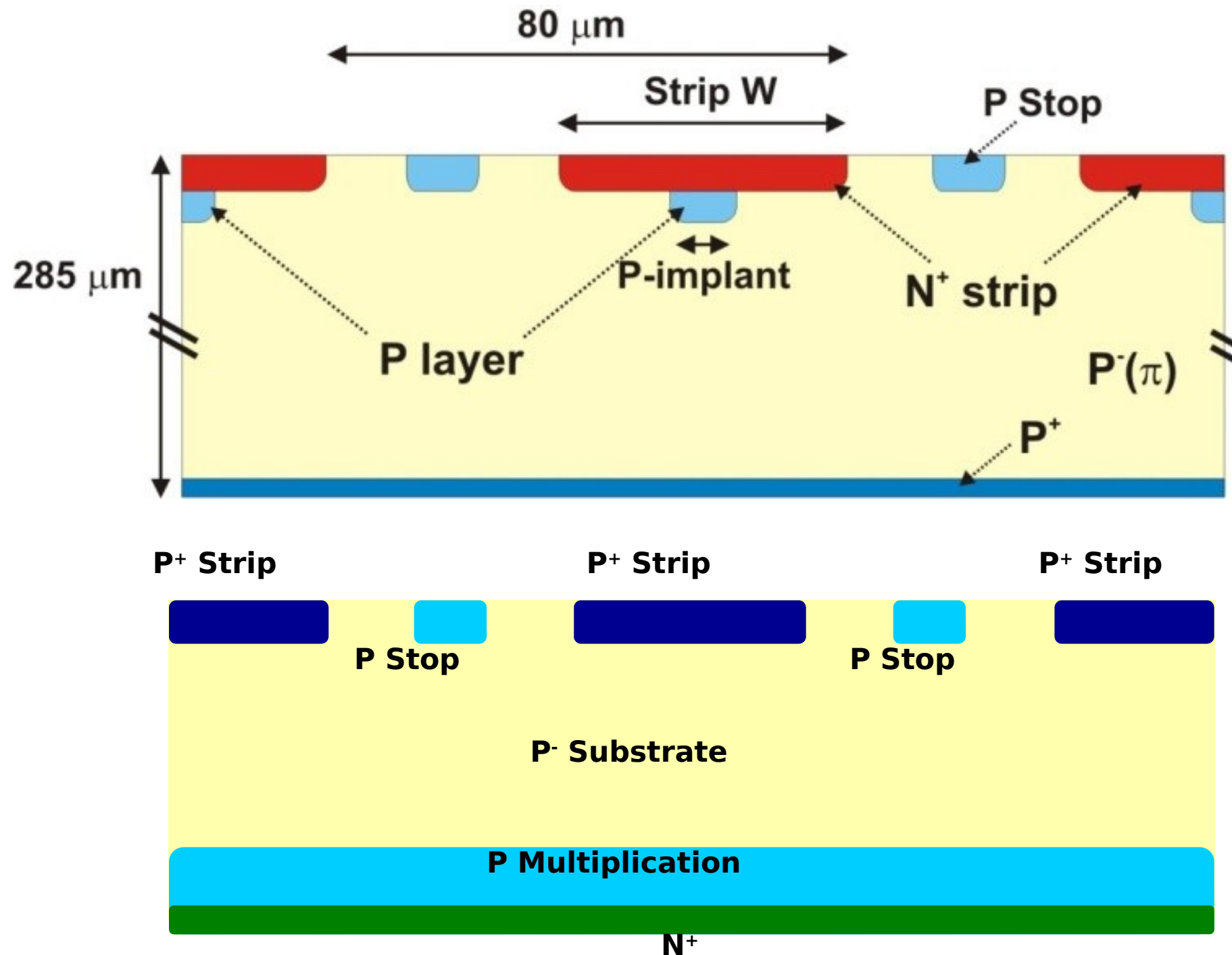


Performed at IFCA in Santander

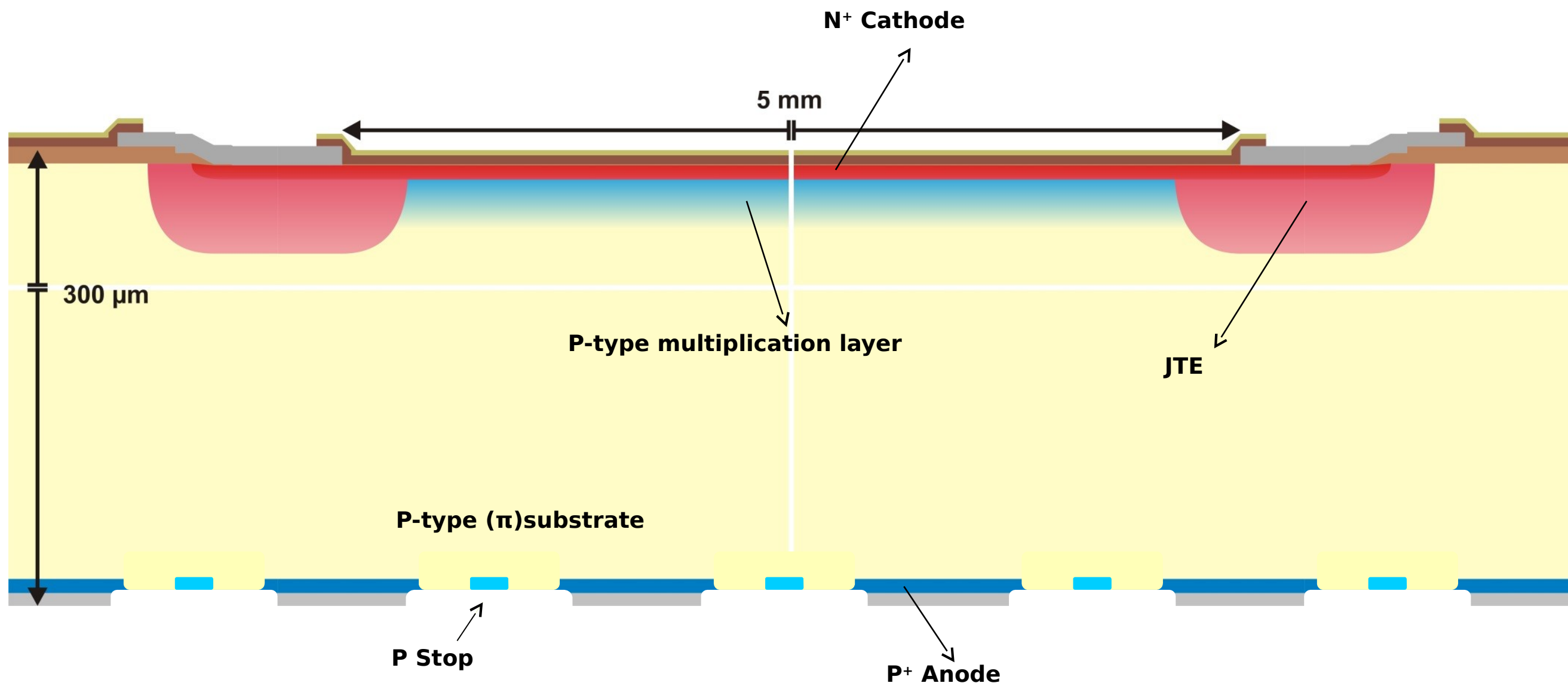




○ **N on P** vs **P on P** **LGAD** microStrips Comparison

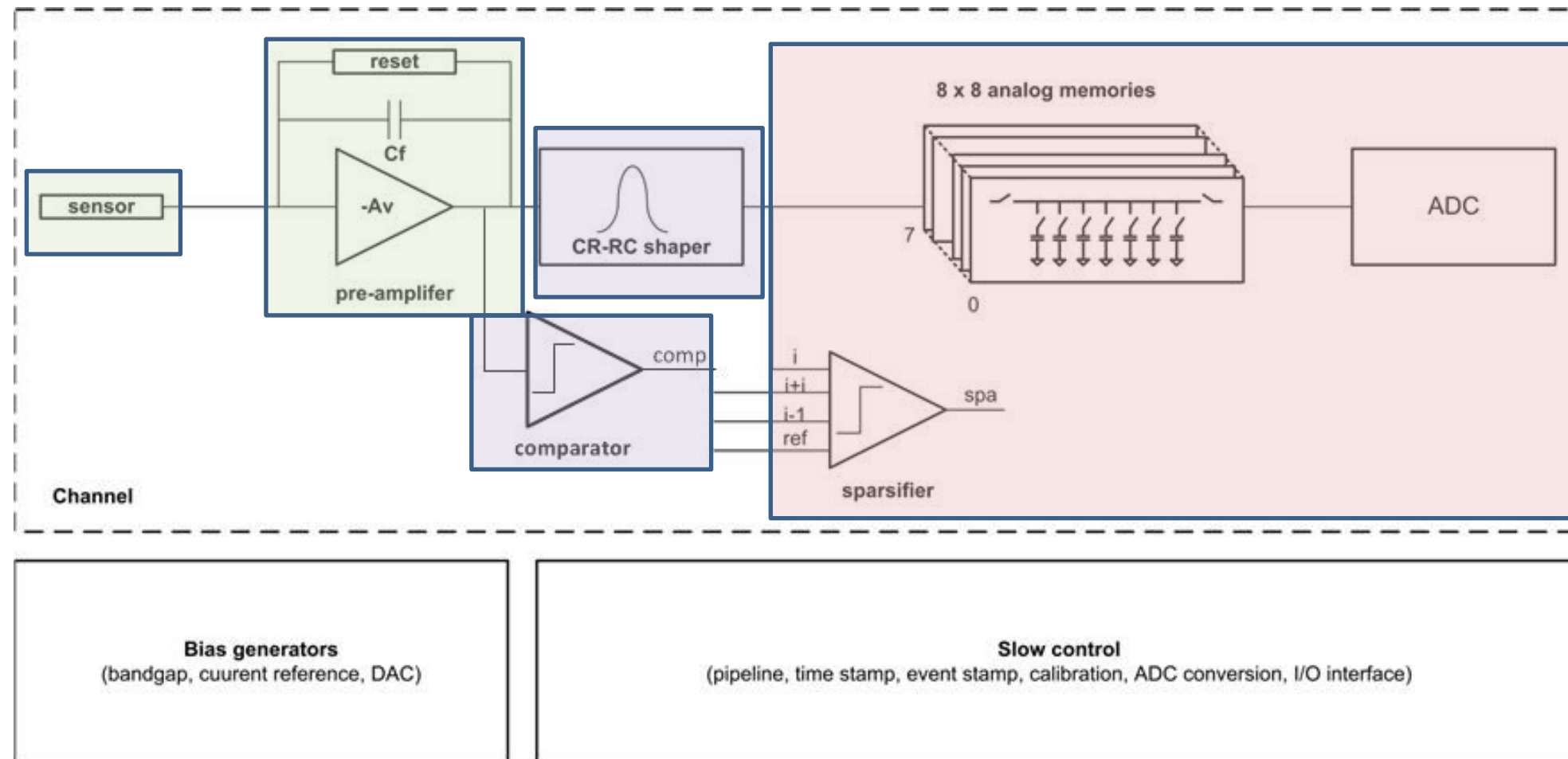


o **Pad Diodes LGAD** with P microStrips at Back Plane





# Current status of FE design



- In progress
- To be designed
- Not included

# Summary

Reported on just two activities, leaving for the next workshop the work on  
*CALICE (see calorimeter session),*  
*EMC & in-situ power regulation*  
*DEPFET progress & FE design*

## **FTD engineered design & mock-up progressing steadily**

DEPFET all-silicon petal prototypes : *Air flow at 1 m/s cools DEPFET, with 1/25 duty cycle pulsed power*

*Dynamic deformations due to pulsed power: none observed, definitively rule out impact this year*

*Vibrations due to air flow: vibrations at few-micron level, work ongoing to raise eigenfrequency above 200 Hz*

## **Diodes with intrinsic gain produced @ CNM in RD50/LGAD**

*Factor 8-10 signal amplification demonstrated*

*Noise unaffected → better S/N and/or less material*

### **Now achieve the same on micro-strips**

*Small gain achieved; careful layout of amplification region needed*

